

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In Re the Application of:

PRAVIN K. NARWANKAR, ET AL.

Application No.: 10/772,893

Filed: February 4, 2004

For: **TAILORING NITROGEN PROFILE IN  
SILICON OXYNITRIDE USING RAPID  
THERMAL ANNEALING WITH  
AMMONIA UNDER ULTRA-LOW  
PRESSURE**

Art Group: 1762

Examiner: Kelly M. Stouffer

Confirmation No.: 5371

**INFORMATION DISCLOSURE STATEMENT UNDER 37 C.F.R. §1.97**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

In accordance with the duty of disclosure, enclosed is a copy of an Information Disclosure Statement (IDS) Citation Form PTO/SB/08 or PTO-1449, together with copies of the documents cited on that form, except for copies not required to be submitted (e.g., copies of U.S. patents and U.S. published patent applications need not be enclosed). This IDS and IDS Citation Form are being submitted concurrently with the Request for Continued Examination. It is respectfully requested that the cited references be considered and that the enclosed copy of PTO/SB/08 be initialed by the Examiner to indicate such consideration and a copy thereof returned to applicant(s).

The submission of this IDS is not to be construed as a representation that a search has been made in the subject application and is not to be construed as an admission that the information cited in this statement is material to patentability.

Please charge any fees due to Deposit Account 02-2666.

Respectfully submitted,

BLAKELY, SOKOLOFF, TAYLOR & ZAFMAN LLP

Date: May 16, 2008

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I hereby certify that this correspondence is being submitted electronically via EFS  
Web on the date shown below.

  
Gigi Hoover

05-16-08

Date